

ELIMINATOR™ CAG

Room Temperature Purifiers for Inert Gases

FEATURES

- Removal of impurities to <0.5 ppb¹
- No heaters or power required
- Room-temperature operation
- 316L SS (<10 Ra EP) vessel
- Factory/Field regenerable for up to 10 year life - no need for H₂ in regeneration gas
- Improved process equipment performance
- Optional built-in 0.003 µm filter (PF type)
- High Flow up to 300 slpm
- Low cost (initial and operating)

The NuPureTM EliminatorTM CAG uses a new, patented Catalyst/Absorber/Getter (CAG) purifier technology, which represents a major improvement over all other inert gas chemistries. This results in the best outlet purity guarantees of <0.5 ppb¹ per impurity². The CAG purifiers achieve this outstanding performance at *room temperature*. They are ideally suited to purifying inert gases from liquid sources.

The NuPure[™] Eliminator[™] CAG gas purifiers come in standard size ranges from 0 to 300 slpm, with the XL version especially suitable for high flow applications. The use of factory-installed inlet isolation valve is recommended for ease of installation, and elimination of possible operator error.

With the purchase of the newly-introduced Field Regeneration Kit, the purifier's operating cost can be reduced to almost zero. Field regeneration is particularly simple and convenient because the CAG can be regenerated *without need for hydrogen!*

Gas	Version	H ₂ O	0 ₂	CO ₂	СО	H ₂	NMHCs	CH ₄	Particles ²
N_2	PF or XL	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	< 1 pcf down to 0.01 μ m
Noble	PF or XL	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	<0.5 ppb	< 1 pcf down to 0.01 µm

IMPURITIES REMOVED¹

1 - Based on VLSI Grade Liquid Gas source. Nitrogen not removed from noble gases. Removal of nitrogen can be accomplished using *heated getter* purifiers. See brochures for NuPure[™] PF Series[®] and Omni[™] Series Gas Purifiers.

2 - Particle removal is guaranteed with PF version only

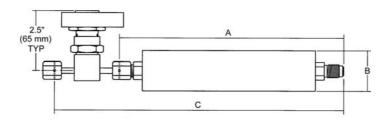


APPLICATIONS

- APIMS Zero and Calibration
- Semiconductor Industry
- Semiconductor Process Equipment
- Gas Cylinder Cabinets
- Gas Analyzer Carts
- Analytical Industry
- Research and Development

NuPure[™] ELIMINATOR[™] CAG

Dimensional and Perfomance Specifications



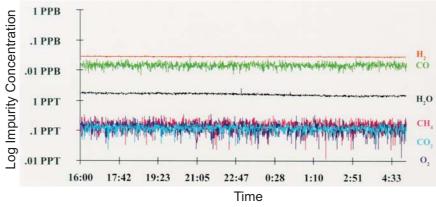
Model	A in (mm)	B in (mm)	C in (mm)	Average Flow @1 yr regeneration	Max Flow ¹ @130 psig
E 40 CAG	5.7 (145)	1.0 (25)	8.5 (216)	0.3 slpm	3 slpm
E 100 CAG	5.7 (145)	1.5 (38)	8.5 (216)	0.8 slpm	8 slpm
E 200 CAG	10 (254)	1.5 (38)	12.8 (325)	2 slpm	20 splm
E 600 CAG	14.6 (371)	2.0 (51)	17.4 (442)	6 slpm	60 slpm
E 1000 CAG	22.1 (561)	2.0 (51)	24.9 (632)	10 slpm	100 slpm
E 2000 CAG	33.1 (841)	2.5 (63)	35.9 (912)	20 slpm	200 slpm
Maximum Press	ure 250 psig (JSA) / 9.9 kg/cm ² G	(Japan) Materials	316L SS (<10 F	Ra EP)
Operating Tempe	erature Room Tem	perature	Fittings	1/4" VCR ²	
Leak Rate	< 2 x 10 ⁻⁹ a	atm cc/sec He	Gas Inlet	VLSI grade (99	.9995% minimum)

1 - Operation at high flow may result in a high pressure drop. Contact factory for technical assistance.

2 - VCR compatible fitting standard. VCR is a Registered Trademark of Cajon Corporation.

NuPure[™] ELIMINATOR[™] Nitrogen Purifier Model 200 CAG @ 5 slpm, 130 psig

Model 200 CAG @ 5 slpm, 130 psig Outlet Purity data as measured by APIMS*



*Tested by a VG Gas Analysis Systems APIMS.

NuPure IIII	Or Contact:
67 Iber Road, Unit 107,	
Ottawa ON K2S 1E7 Canada	
Tel: (613) 836-0336 Fax: (613) 836-0297	
E-mail: sales@nupure.com Web-site: www.nupure.com	